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INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION

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APPLICANT
Xuelong SHI, et al.

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GROUP
2825

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code(s) (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
NL	US	5,621,652	04/15/1997	Eakin	
NL	US	5,682,323	10/28/1997	Pasch et al.	
	US	5,821,014	10/13/1998	Chen et al.	
	US	6,077,310	06/20/2000	Yamamoto et al.	
	US	6,078,738	06/20/2000	Garza et al.	
	US	6,421,820 B1	07/16/2002	Mansfield et al.	
	US	6,541,167 B2	04/01/2003	Petersen et al.	
NL	US	20020004714 A1	01/10/2002	Jones et al.	
NL	US	20030082463 A1	05/01/2003	Lalidig et al.	
	US				

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Code-Number +-Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
NL		WO 99/14638	03/25/1999	NUMERICAL TECHNOLOGIES, INC.		x	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	
NL		HEWAK, Daniel, et al. "Fabrication of tapers and lenslike waveguides by a microcontrolled dip coating procedure." <i>Applied Optics</i> , Volume 27, Number 21, November 1, 1988, pp. 4562-4564	
NL		TORRES, J.A., et al. "Contrast-based assist feature optimization photolithography." <i>Optical Microlithography XV</i> , Santa Clara CA, March 5-8 2002, Volume 4691, pp. 179-187, XP 000118758, ISSN: 0277-788X	

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